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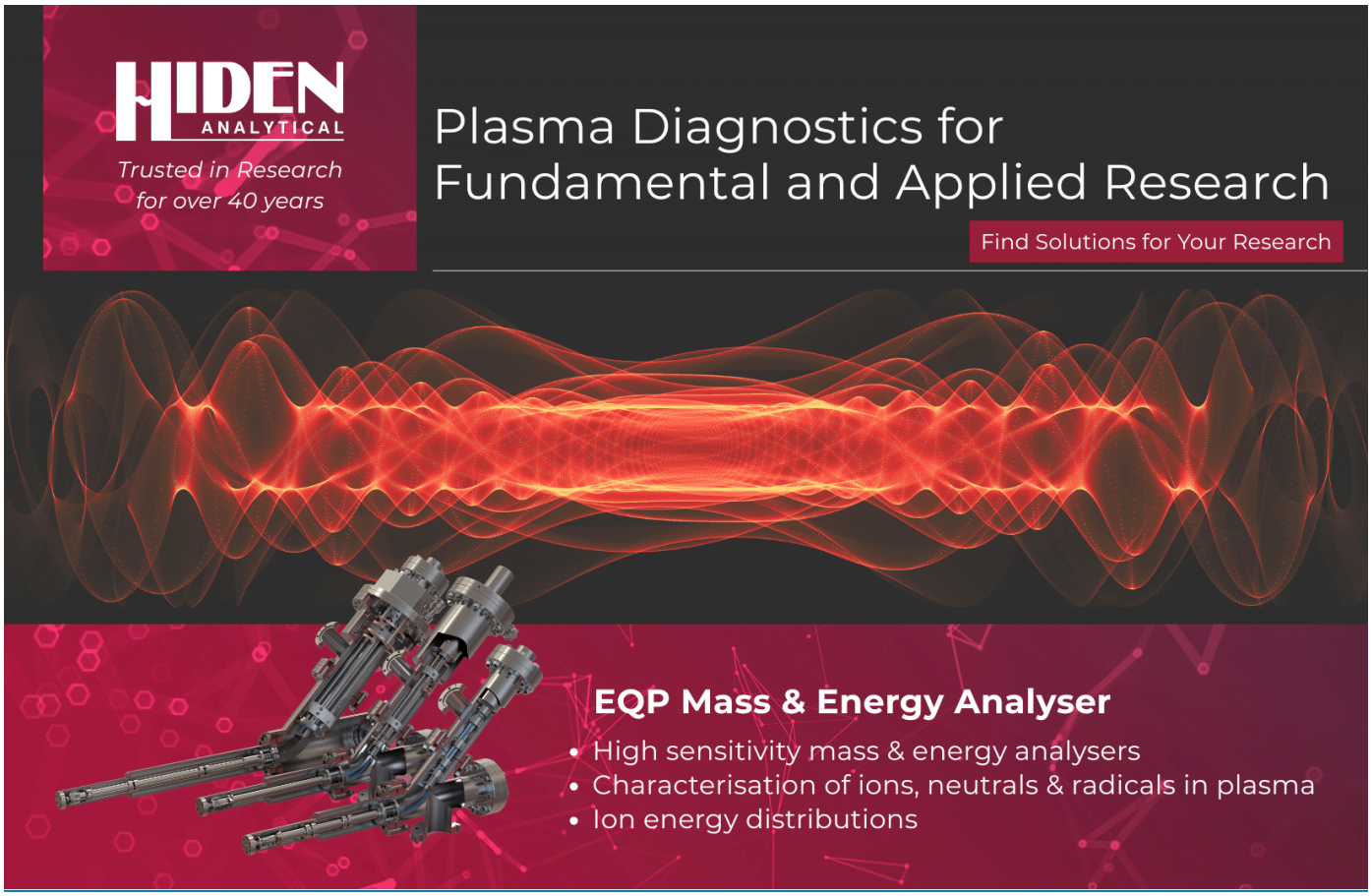

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Plasma Sources Science and Technology

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RECEIVED
15 July 2026

ACCEPTED FOR PUBLICATION
29 July 2026

PUBLISHED
27 October 2026

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In the original version of this article, the Acknowledgment section on p. 8 contains an incorrect Grant Number (RS-2023-00237362). The grant number should be revised to RS-2023-00237543. Therefore, the Acknowledgments should be revised as below:

Acknowledgments

This work was supported by a National Research Foundation of Korea (NRF) grant funded by the Korea government (MSIT) (Nos. RS-2023-00260527 and RS-2023-00237543), the Ministry of Trade, Industry & Energy (20020392, 20022472, 1415187403, 20024017, and 00154752), and the Korea Semiconductor Research Consortium (KSRC) (RS-2023 00235950) support program for the development of future semiconductor devices.

This correction does not alter the contents of this article, including the results, discussions, and conclusions.

Data availability statement

No new data were created or analysed in this study.

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